Lecture 23: Scaling and Economics

Mark McDermott

Electrical and Computer Engineering The University of Texas at Austin

Agenda

Scaling

- Transistors
- Interconnect
- Future Challenges

VLSI Economics

Moore's Law

- In 1965, Gordon Moore predicted the exponential growth of the number of transistors on an IC
- Transistor count doubled every year since invention
- Predicted > 65,000 transistors by 1975!
- Growth limited by power



Transistor counts have doubled every 26 months for the past four decades.



Clock frequencies have also increased exponentially A corollary of Moore's Law (until about 6 years ago)



Scaling

The only constant in VLSI is constant change

Feature size shrinks by 30% every 2-3 years

- Transistors become cheaper
- Transistors become faster
- Wires do not improve (and may get worse)

Scale factor S

- Typically $S \approx \sqrt{2}$
- Technology nodes



Scaling Assumptions

What changes between technology nodes?

Constant Field Scaling

- All dimensions: x, y, z => W/S, L/S, t_{ox}/S
- Voltage Scales: V_{DD}/S
- Doping levels: S*N_a, S*N_d
- Electric Field does not scale (= 1)

Lateral Scaling

- Only gate length: L
- Often done as a quick gate shrink (S = 1.05)

Constant Voltage Scaling

- All dimensions: x, y, z => W/S, L/S, t_{ox}/S
- Voltage does not scale
- Doping levels: S²*N_a, S²*N_d
- Electric Field increases by S

Device Scaling

Parameter	Sensitivity	Dennard Scaling
L: Length		1/S
W: Width		1/S
t _{ox} : gate oxide thickness		1/S
V _{DD} : supply voltage		1/S
V _t : threshold voltage		1/S
NA: substrate doping		S
β	W/(Lt _{ox})	S
I _{on} : ON current	$\beta (V_{DD}-V_t)^2$	1/S
R: effective resistance	V _{DD} /I _{on}	1
C: gate capacitance	WL/t _{ox}	1/S
τ: gate delay	RC	1/S
f: clock frequency	1/τ	S
E: switching energy / gate	CV _{DD} ²	1/S ³
P: switching power / gate	Ef	1/S ²
A: area per gate	WL	1/S ²
Switching power density	P/A	1
Switching current density	I _{on} /A	S

Traditional Planar Transistor



Traditional 2-D planar transistors form a conducting channel on the silicon surface under the gate electrode

22 nm FIN-FET Transistor



3-D Tri-Gate transistors form conducting channels on three sides of a vertical silicon fin

22 nm FIN-FET Transistor



Tri-Gate transistors can connect together multiple fins for higher drive current and higher performance

22 nm FIN-FET Transistors



Tri-Gate transistors are "fully depleted" devices that have improved operating characteristics

Observations

- Gate capacitance per micron is nearly independent of process
- But ON resistance * micron improves with process
- Gates get faster with scaling (good)
- Dynamic power goes down with scaling (good)
- Current density goes up with scaling (bad)
- Velocity saturation makes lateral scaling unsustainable

Interconnect Scaling Assumptions

Wire thickness

- Hold constant vs. reduce in thickness
- Wire length
 - Local / scaled interconnect
 - Global interconnect
 - Die size scaled by $D_c \approx 1.1$

Interconnect Scaling

Table 4.16 Influence of scaling on interconnect characteristics								
Parameter	Sensitivity	Reduced Thickness	Constant Thickness					
Scaling Parameters								
Width: w 1/S								
Spacing: s		1/S						
Thickness: t		1/S	1					
Interlayer oxide height: h		1/S						
Characteristics Per Unit Length								
Wire resistance per unit length: R_w	$\frac{1}{wt}$	S^2	S					
Fringing capacitance per unit length: $C_{w\!f}$	$\frac{t}{s}$	1	S					
Parallel plate capacitance per unit length: C_{wp}	$\frac{w}{b}$	1	1					
Total wire capacitance per unit length: $C_{\!w}$	C_{wf} + C_{wp}	1	between 1, S					
Unrepeated RC constant per unit length: t_{wu}	$R_w C_w$	S^2	between <i>S</i> , <i>S</i> ²					
Repeated wire RC delay per unit length: t_{wr} (assuming constant field scaling of gates in Table 4.15)	$\sqrt{RCR_wC_w}$	\sqrt{s}	between 1, \sqrt{S}					
Crosstalk noise	$\frac{t}{s}$	1	S					

Interconnect Delay

Table 4.16 Influence of scaling on interconnect characteristics							
Parameter	Sensitivity	Reduced Thickness	Constant Thickness				
Scaling Parameters							
Width: w		1/S					
Spacing: s		1/S					
Thickness: t		1/S	1				
Interlayer oxide height: <i>h</i>		1/S					
Local/Scaled Interconnect Characteristics							
Length: /		1/S					
Unrepeated wire RC delay	$l^2 t_{wu}$	1	between 1/S, 1				
Repeated wire delay	lt _{wr}	$\sqrt{1/S}$	between $1/S, \sqrt{1/S}$				
Global Interconnect Characteristics							
Length: /		D_{c}					
Unrepeated wire RC delay	$l^2 t_{wu}$	$S^2 D_c^2$	between $SD_c^2, S^2D_c^2$				
Repeated wire delay	lt _{wr}	$D_c \sqrt{S}$	between D_c , $D_c \sqrt{S}$				

Interconnect Observations

Capacitance per micron is remaining constant

- About 0.2 fF/ μ m
- Roughly 1/10 of gate capacitance
- Local wires are getting faster
 - Not quite tracking transistor improvement
 - But not a major problem
- Global wires are getting slower
 - No longer possible to cross chip in one cycle

Intl. Technology Roadmap for Semiconductors

Table 4.17 Predictions from the 2002 ITRS								
Year	2001	2004	2007	2010	2013	2016		
Feature size (nm)	130	90	65	45	32	22		
$V_{DD}(\mathbf{V})$	1.1-1.2	1-1.2	0.7–1.1	0.6-1.0	0.5–0.9	0.4–0.9		
Millions of transistors/die	193	385	773	1564	3092	6184		
Wiring levels	8-10	9–13	10-14	10-14	11–15	11–15		
Intermediate wire pitch (nm)	450	275	195	135	95	65		
Interconnect dielectric	3–3.6	2.6-3.1	2.3–2.7	2.1	1.9	1.8		
constant								
I/O signals	1024	1024	1024	1280	1408	1472		
Clock rate (MHz)	1684	3990	6739	11511	19348	28751		
FO4 delays/cycle	13.7	8.4	6.8	5.8	4.8	4.7		
Maximum power (W)	130	160	190	218	251	288		
DRAM capacity (Gbits)	0.5	1	4	8	32	64		

Scaling Implications

- Improved Performance
- Improved Cost
- Interconnect Woes
- Power Woes
- Productivity Challenges
- Physical Limits

In 2003, \$0.01 bought you 100,000 transistors

- Moore's Law is still going strong



Interconnect Woes

SIA made a gloomy forecast in 1997

Delay would reach minimum at 250 – 180 nm, then get worse because of wires

But...



Interconnect Woes

SIA made a gloomy forecast in 1997

- Delay would reach minimum at 250 180 nm, then get worse because of wires
- But...
 - Misleading scale
 - Global wires
- 100k gate blocks ok



Reachable Radius

- We can't send a signal across a large fast chip in one cycle anymore
- But the microarchitect can plan around this
 - Just as off-chip memory latencies were tolerated



Dynamic Power

Intel's Patrick Gelsinger (ISSCC 2001)

- If scaling continues at present pace, by 2005, high speed processors would have power density of nuclear reactor, by 2010, a rocket nozzle, and by 2015, surface of sun.
- "Business as usual will not work in the future."
- Intel stock dropped 8% on the next day
- But attention to power is increasing



Static Power

- V_{DD} decreases
 - Save dynamic power
 - Protect thin gate oxides and short channels
 - No point in high value because of velocity sat.
- V_t must decrease to
 - maintain device performance
- But this causes exponential increase in OFF leakage
- Major future challenge



Productivity

Transistor count is increasing faster than designer productivity (gates / week)

- Bigger design teams
 - Up to 500 for a high-end microprocessor
- More expensive design cost
- Pressure to raise productivity
 - Rely on synthesis, IP blocks
- Need for good engineering managers



Increasing Design Cost



Source: ITRS 2003

Physical Limits

Will Moore's Law run out of steam?

– Can't build transistors smaller than an atom...

Many reasons have been predicted for end of scaling

- Dynamic power
- Subthreshold leakage, tunneling
- Short channel effects
- Fabrication costs
- Electromigration
- Interconnect delay

Rumors of immediate demise have been exaggerated

- Smart engineers continue push the walls out to the next generation
- But, still can't build transistors smaller than an atom

VLSI Economics

- Selling price S_{total}
 S_{total} = C_{total} / (1-m)
- m = profit margin
- C_{total} = total cost
 - Nonrecurring engineering cost (NRE)
 - Recurring costs
 - Fixed costs

NRE

Engineering cost

- Depends on size of design team
- Include benefits, training, computers
- CAD tools:
 - Digital front end: \$10K
 - Analog front end: \$100K
 - Digital back end: \$1M

Prototype manufacturing

- Mask costs: \$500k 1M in 130 nm process
- Test fixture and package tooling



Recurring Costs (Cont)

- Fabrication
 - Wafer cost / (Dice per wafer * Yield)
 - Wafer cost: \$500 \$3000
- Yield analysis
 - Example
 - wafer size of 12 inches, die size of 2.5 cm2, 1 defect/cm2,
 - α = 3 (measure of manufacturing process complexity)
 - 252 die/wafer (remember, wafers round & dies square)
 - die yield of 16%
 - 252 x 16% = only 40 die/wafer yield
- Packaging
- Test

Fixed Costs

- Marketing and advertising
- Travel
- Coffee bar
- Weekly massages

Chip	Metal layers	Line width	Wafer cost	Defects /cm²	Area (mm²)	Dies/ wafer	Yield	Die cost
386DX	2	0.90	\$900	1.0	43	360	71%	\$4
486DX2	3	0.80	\$1200	1.0	81	181	54%	\$12
PowerPC 601	4	0.80	\$1700	1.3	121	115	28%	\$53
HP PA 7100	3	0.80	\$1300	1.0	196	66	27%	\$73
DEC Alpha	3	0.70	\$1500	1.2	234	53	19%	\$149
Super SPARC	3	0.70	\$1700	1.6	256	48	13%	\$272
Pentium	3	0.80	\$1500	1.5	296	40	9%	\$417

Generalized Cost Curve



Idealized Cost & Revenue Model



More Probable Revenue Model



Revenue Lost Because of Product Delay



Example

- You want to start a company to build a wireless communications chip. How much venture capital must you raise?
- Because you are smarter than everyone else, you can get away with a small team in just two years:
 - Seven digital designers
 - Three analog designers
 - Five support personnel

Solution

Digital designers:

- \$70k salary
- \$30k overhead
- \$10k computer
- \$10k CAD tools
- Total: \$120k * 7 = \$840k
- Analog designers
 - \$100k salary
 - \$30k overhead
 - \$10k computer
 - \$100k CAD tools
 - Total: \$240k * 3 = \$720k

Support staff

- \$45k salary
- \$20k overhead
- \$5k computer
- Total: \$70k * 5 = \$350k
- Fabrication
 - Back-end tools: \$1M
 - Masks: \$1M
 - Total: \$2M / year
- Summary
 - 2 years @ \$3.91M / year
 - \$8M design & prototype

New chip design is fairly capital-intensive

Can you do it for less?



Questions??